

AMENDMENTS TO THE SPECIFICATION

A. Please replace the paragraph beginning at line 12 of page 8 with the following paragraph:

The present invention relates to a magnetically coupled linear servo-drive mechanism. The invention is suitable for use in a wide variety of semiconductor manufacturing equipment such as, without limitation, those used for chemical vapor deposition, etching, physical vapor deposition, lithography, chemical-mechanical planarization, etc. In one embodiment, the present invention is employed in the wafer processing system disclosed in the commonly assigned US Application _____ 09/888,017, entitled "High Throughput Architecture For Semiconductor Processing", attorney docket no. 50544.00003, filed June 21, 2001 by Craig L. Stevens. The just mentioned US Application is incorporated herein by reference in its entirety.

B. Please replace the paragraph beginning at line 17 of page 17 with the following paragraph:

The entire interior of load lock 7000 is maintained at a vacuum to prevent contamination of the wafers. The servo motor 2010 and timing belt/pulley set 2030 are located exterior to load lock 7000 to further prevent contamination of the wafers. Further details about load lock 7000 can be found in U.S. Patent Application No. _____, _____ filed on _____ 09/888,017, and entitled "High Throughput Architecture for Semiconductor Processing," by inventor Craig L. Stevens, which is incorporated by reference.